



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)	MAIL STOP AF
Kazuya KAMON)	Group Art Unit: 1756
Application No.: 09/320,946)	Examiner: S. Mohamedulla
Filed: May 26, 1999)	Confirmation No.: 5658
For: PHOTOMASK, FABRICATION METHOD OF PHOTOMASK, AND FABRICATION METHOD OF SEMICONDUCTOR INTEGRATED CIRCUIT	·)	

AMENDMENT UNDER 37 C.F.R. §1.116

Date: November 10, 2003

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This Amendment responds to the Office dated August 13, 2003 (Paper No. 23).

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Please amend the above-identified application as follows:

to enter -SPM 12/23/03

11/12/2003 HDEMESS1 00000095 09320946 01 FC:1201 1118.00 GP

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